IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: To Be Assigned Examiner: To Be Assigned

In re PATENT APPLICATION of

Applicant(s): Noriko TOMITA et al.

Serial No.: To Be Assigned

Filed: September 12, 2003 (herewith)

For: SEMICONDUCTOR SUBSTRATE SURFACE

PROTECTION METHOD

Atty. Dkt.: OHG 135

September 12, 2003

) INFORMATION

DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

This is an information disclosure statement submitted in compliance with the timing requirements of 37 C.F.R. §1.97(b)(1).

Attached are copies of two (2) Japanese publications. One publication is discussed on page 6 of the application, where any relevance thereof can be ascertained. Any relevance of the other publication can be gleaned from its drawings, which include English-language notations. The references are listed on the attached Form PTO-1449.

Since this Information Disclosure Statement is being filed with the application, no certification or fee is required, and the requirements of 37 C.F.R. §§1.97 and 1.98 are deemed to be fully met as to the documents submitted. Consideration of the submitted documents is respectfully requested.

September 12, 2003

Date

NO ON

Respectfully submitted,

Robert H. Berdo, Jr. Registration No. 38,075 RABIN & BERDO, PC Customer No. 23995

Telephone: 202-371-8976 Facsimile: 202-408-0924

FORM PTO-1449 INFORMATION DISCLOSURE STA- TEMENT				Atty. Docket: OHG-135	Application No.: Not y t assigned		
				Applicant: Noriko TOMITA et al.			
				Filing Date: September 12, 2003	Group Art Unit: Not yet assigned		
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub- Class	Filing Date
	AA						
	AB						
	AC						
	AD						
	AE			781-			
	AF			A STATE OF THE STA			
	AG						
	АН						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Sub- Class	Trans- Lation
	AI						
	AJ						
	AK						
	AL						
	AM						
		OTHER (Ir	ncluding Au	thor, Title, Date, Pertinen	t Pages, etc.)		
	AN	"Chemical Contamination in the semiconductor process environment and countermeasures therefor". Realize Inc., pp. 268-269 (page 6 of the specification)					
	AO	"The current status of contamination in the ULSI fabricating". Realize Inc., pp. 378-383					
Examiner Date Considered							
EVAMINED	. Initia	al if reference	oonoidarad u	hothor or not citation is in cor	formana with NAT	DED 600.	al

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.